



<b>Organisation Chain :</b>	Indian Institute of Technology Madras  Deputy Registrar (Industrial Consultancy and Sponsored Research)
<b>Tender ID :</b>	2021_IIT-M_589583_1
<b>Tender Ref No :</b>	EE/2021/043/ENAK/PEALD SYSTEM
<b>Tender Title :</b>	Plasma enhanced Atomic Layer Deposition (PEALD) system suitable for deposition of Al <sub>2</sub> O <sub>3</sub> , AlHfO, AlN, SiO <sub>2</sub> and SiN
<b>Corrigendum Type :</b>	Date

**Corrigendum:1**

Corrigendum Title	Corrigendum Description	Published Date	Document Name	Doc Size(in KB)
Corrigendum - 1	Changes in technical specification and Extension of Bid Submission Date	25-Feb-2021 12:12 PM	<a href="#">CORRIGENDUM - 1.pdf</a>	394.34

**Critical Dates**

<b>Publish Date</b>	12-Feb-2021 01:20 PM	<b>Bid Opening Date</b>	12-Mar-2021 04:00 PM
<b>Document Download/Sale Start Date</b>	12-Feb-2021 01:30 PM	<b>Document Download/Sale End Date</b>	11-Mar-2021 05:00 PM
<b>Clarification Start Date</b>	NA	<b>Clarification End Date</b>	NA
<b>Bid Submission Start Date</b>	15-Feb-2021 09:00 AM	<b>Bid Submission End Date</b>	11-Mar-2021 05:00 PM

**Details Before Corrigendum**

<b>Critical Dates</b>			
<b>Publish Date</b>	12-Feb-2021 01:20 PM	<b>Bid Opening Date</b>	05-Mar-2021 04:00 PM
<b>Document Download/Sale Start Date</b>	12-Feb-2021 01:30 PM	<b>Document Download/Sale End Date</b>	04-Mar-2021 05:00 PM
<b>Clarification Start Date</b>	NA	<b>Clarification End Date</b>	NA
<b>Bid Submission Start Date</b>	15-Feb-2021 09:00 AM	<b>Bid Submission End Date</b>	04-Mar-2021 05:00 PM